SCHEDULE 1

PROHIBITED GOODS

PART III

GROUP 3

INDUSTRIAL GOODS

Technology

2E.—(2E001) **Technology required** for the **development** of **goods** specified in sub-categories 2A, 2B or 2D.

- (2E002) Technology required for the production of goods specified in sub-categories 2A or 2B.
- (2E003) Other technology, as follows:
 - (a) **Technology:**
 - (1) For the **development** of interactive graphics as an integrated part in **numerical control** units for preparation or modification of part programmes;
 - (2) For the **development** of generators of machine tool instructions (e.g., part programmes) from design data residing inside **numerical control** units;
 - (3) For the **development** of integration **software** for incorporation of expert systems for advanced decision support of shop floor operations into **numerical control** units;
 - (b) Technology for metal-working manufacturing processes, as follows:
 - (1) **Technology** for the design of tools, dies or fixtures specially designed for the following processes:
 - (a) Superplastic forming;
 - (b) **Diffusion bonding**;
 - (c) Direct-acting hydraulic pressing;
 - (2) Technical data consisting of process methods or parameters as listed below used to control:
 - (a) Superplastic forming of aluminium alloys, titanium alloys or superalloys:
 - (1) Surface preparation;
 - (2) Strain rate;
 - (3) Temperature;
 - (4) Pressure;
 - (b) **Diffusion bonding** of **superalloys** or titanium alloys:
 - (1) Surface preparation;
 - (2) Temperature;
 - (3) Pressure;
 - (c) Direct-acting hydraulic pressing of aluminium alloys or titanium alloys:
 - (1) Pressure;
 - (2) Cycle time;

- (d) Hot isostatic densification of titanium alloys, aluminium alloys or superalloys:
- (1) Temperature;
- (2) Pressure;
- (3) Cycle time;
- (c) **Technology** for the **development** or **production** of hydraulic stretch-forming machines and dies therefor, for the manufacture of airframe structures;
- (d) **Technology** for:

The application of inorganic overlay coatings or inorganic surface modification coatings, specified in column 3 of the following Table;

To non-elecronic substrates, specified in column 2 of the following Table; By processes specified in column 1 of the following Table and defined in the Note.

TABLE—

DEPOSITION TECHNIQUES

1	2	3
Coating Process (1)	Substrate	Resultant Coating
(A) Chemical Vapour Deposition (CVD)	r Superalloys	Aluminides for internal passages
	Ceramics and low-expansion glasses(14)	Silicides
		Carbides
		Dielectric layers (15)
	Carbon-carbon, ceramic and metal matrix composites	Silicides
		Carbides
		Refractory metals
		Mixtures thereof (4)
		Dielectric layers (15)
		Aluminides
		Alloyed aluminides (2)
	Cemented tungsten carbide (16), silicon carbide	Carbides
		Tungsten
		Mixtures thereof (4)
		Dielectric layers (15)
	Molybdenum and molybdenum alloys	Dielectric layers (15)

1	2	3
Coating Process (1)	Substrate	Resultant Coating
	Beryllium and beryllium alloys	Dielectric layers (15)
(B) Thermal-Evaporation Physical Vapour Deposition (TE-PVD)	Sensor window materials (9)	Dielectric layers (15)
(1) (1) Physical Vapour Deposition (PVD): Electron- Beam (EB-PVD)	Superalloys	Alloyed silicides
		Alloyed aluminides (2)
		MCrA1X (5)
		Modified zirconia (12)
		Silicides
		Aluminides
		Mixtures thereof (4)
	Ceramics and low-expansion glasses (14)	Dielectric layers (15)
	Corrosion resistant steel (7)	MCrA1X (5)
		Modified zirconia (12)
		Mixtures thereof (4)
	Carbon-carbon, ceramic and metal matrix composites	Silicides
		Carbides
		Refractory metals
		Mixtures thereof (4)
		Dielectric layers (15)
	Cemented tungsten carbide (16), silicon carbide	Carbides
		Tungsten
		Mixtures thereof (4)
		Dielectric layers (15)
	Molybdenum and molybdenum alloys	Dielectric layers (15)
	Beryllium and beryllium alloys	Dielectric layers (15)

a (The numbers in parenthesis refer to the Notes following this Table.)

	2	3
oating Process (1)	Substrate	Resultant Coating
		Borides
	Sensor window materials (9)	Dielectric layers (15)
	Titanium alloys (13)	Borides
		Nitrides
		Dielectric layers (15)
	Carbon-carbon, ceramic and metal matrix composites	Dielectric layers (15)
	Cemented tungsten carbide (16), silicon carbide	Dielectric layers (15)
	Molybdenum and molybdenum alloys	Dielectric layers (15)
	Beryllium and beryllium alloys	Dielectric layers (15)
	Sensor window materials (9)	Dielectric layers (15)
(B.3) (B.3) Physical Vapour Deposition: laser evaporation	Ceramics and low-expansion glasses (14)	Silicides
		Dielectric layers (15)
	Carbon-carbon, ceramic and metal matrix composites	Dielectric layers (15)
	Cemented tungsten carbide (16), silicon carbide	Dielectric layers (15)
	Molybdenum and molybdenum alloys	Dielectric layers (15)
	Beryllium and beryllium alloys	Dielectric layers (15)
	Sensor window materials (9)	Dielectric layers (15)
		Diamond-like carbon
Vapour	Superalloys	Alloyed silicides
Deposition: cathodic arc discharge		

a (The numbers in parenthesis refer to the Notes following this Table.)

1	2	3
Coating Process (1)	Substrate	Resultant Coating
		Alloyed aluminides (2)
		MCrA1X (5)
	Polymers (11) and organic matrix composites	Borides
		Carbides
		Nitrides
	Carbon-carbon, ceramic and metal matrix composites	Silicides
		Carbides
		Mixtures thereof (4)
	Titanium alloys (13)	Silicides
		Aluminides
		Alloyed aluminides (2)
	Refractory metals and alloys (8)	Silicides
		Oxides
D. Plasma spraying	Superalloys	MCrA1X (5)
		Modified zirconia (12)
		Mixtures thereof (4)
		Abradable Nickel-Graphite
		Abradable Ni-Cr-Al- Bentonite
		Abradable Al-Si-Polyester
		Alloyed aluminides (2)
	Aluminium alloys (6)	MCrA1X (5)
		Modified zirconia (12)
		Silicides
		Mixtures thereof (4)
	Refractory metals and alloys (8)	Aluminides
		Silicides
		Carbides

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1	2	3
Coating Process (1)	Substrate	Resultant Coating
	Corrosion resistant steel (7)	Modified zirconia (12)
		Mixtures thereof (4)
	Titanium alloys (13)	Carbides
		Aluminides
		Silicides
		Alloyed aluminides (2)
		Abradable Nickel-Graphite
		Abradable Ni-Cr-Al- Bentonite
		Abradable Al-Si-Polyester
E. Slurry Deposition	Refractory metals and alloys (8)	Fused silicides
		Fused aluminides except for resistance heating elements
	Carbon-carbon, ceramic and metal matrix composites	Silicides
		Carbides
		Mixtures thereof (4)
F. Sputter Deposition	Superalloys	Alloyed silicides
		Alloyed aluminides (2)
		Noble metal modified aluminides (3)
		MCrA1X (5)
		Modified zirconia (12)
		Platinum
		Mixtures thereof (4)
	Ceramics and low-expansion glasses (14)	Silicides
		Platinum
		Mixtures thereof (4)
		Dielectric layers (15)
	Titanium alloys (13)	Borides
		Nitrides
		Oxides

1	2	3
Coating Process (1)	Substrate	Resultant Coating
		Silicides
		Aluminides
		Alloyed aluminides (2)
		Carbides
	Carbon-carbon, ceramic and metal matrix composites	Silicides
		Carbides
		Refractory metals
		Mixtures thereof (4)
		Dielectric layers (15)
	Cemented tungsten carbide (16), silicon carbide	Carbides
		Tungsten
		Mixtures thereof (4)
		Dielectric layers (15)
	Molybdenum and molybdenum alloys	Dielectric layers (15)
Beryllium and beryllium Illoys	Borides	
Sensor window materials (9)	Dielectric layers (15)	
		Dielectric layers (15)
	Refractory metals and alloys (8)	Aluminides
		Silicides
		Oxides
		Carbides
G. Ion Implantation	High temperature bearing steels	Additions of chromium tantalum or niobium (columbium)
	Titanium alloys (13)	Borides
		Nitrides
	Beryllium and beryllium alloys	Borides
	Cemented tungsten carbide(16)	Carbides

1	2	3
Coating Process (1)	Substrate	Resultant Coating
		Nitrides
a (The numbers in parenthesis	s refer to the Notes following this	Table.)